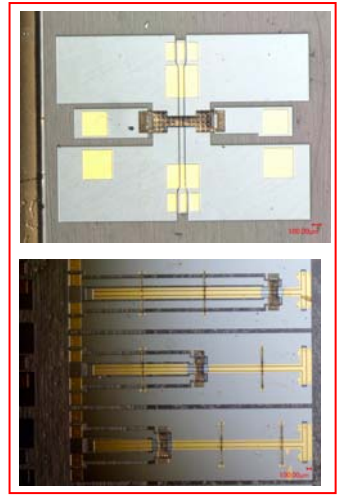
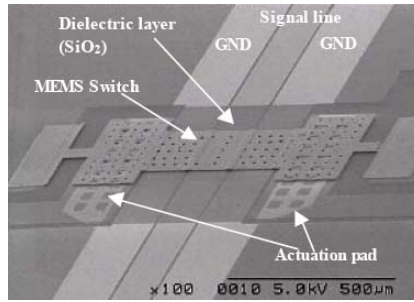
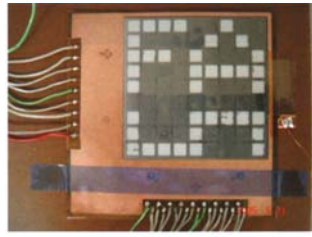
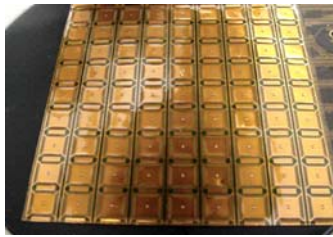
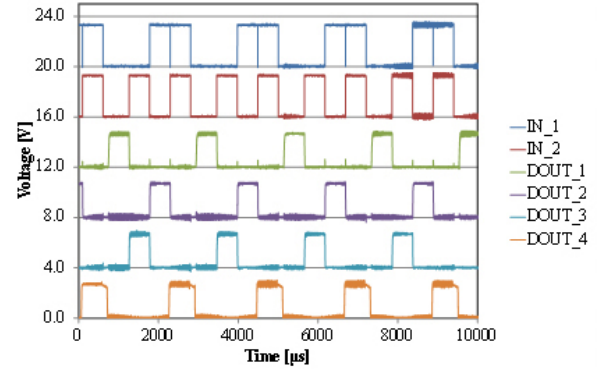
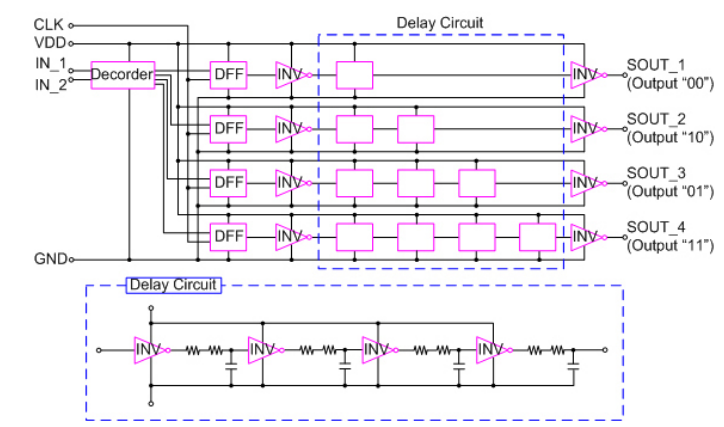
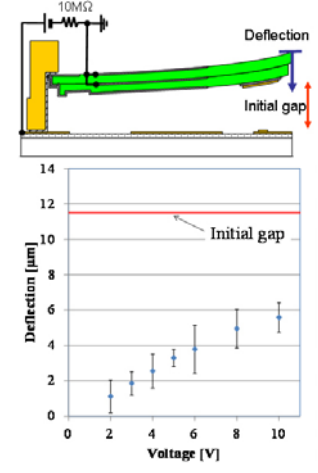
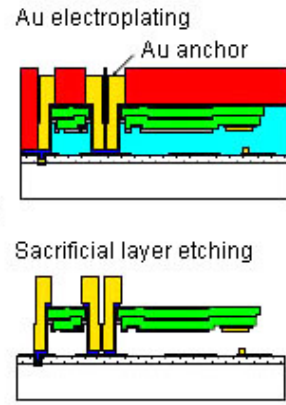
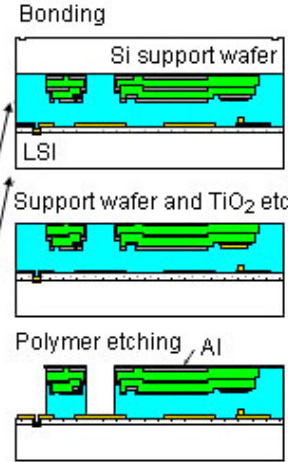
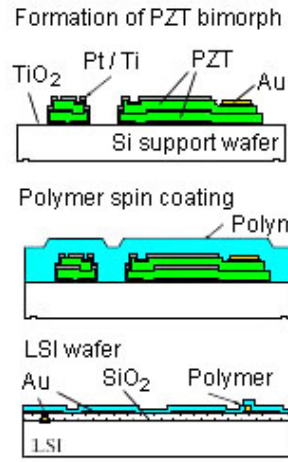
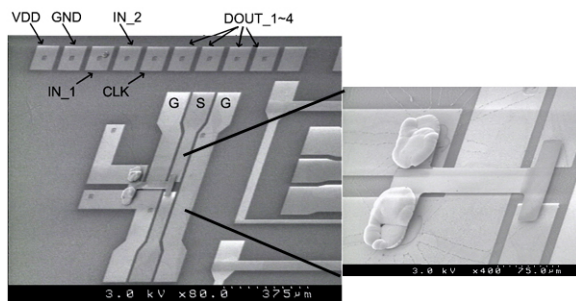
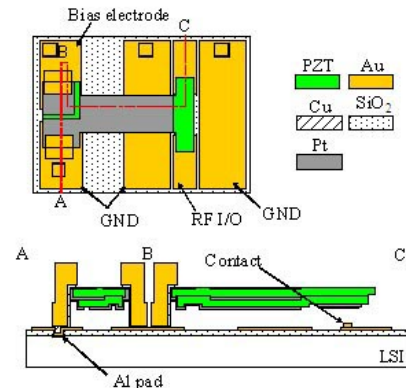


# MEMS Switch (Electrostatic and Piezoelectric)



E ink display using electrostatically actuated MEMS switch (Inside the case) Electrostatically actuated capacitive switch

Reference : T.Yuki, J.H.Kuypers, S.Tanaka and M.Esashi, Capacitive RF Switch Fabricated by Low-temperature Surface Process and Packaged Using Dry Film Resist, Proc. of the 24th Sensor Symp. (2007) pp.37-40



MEMS switch using piezoelectric thin film

Reference : K.Matsuo, M.Moriyama, M.Esashi and S.Tanaka, Low-voltage PZT-actuated MEMS Switch Monolithically Integrated with CMOS Circuit, Technical Digest IEEE MEMS 2012 (2012) pp.1153-1156